I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Putants, Washington, D.C. 20231, on

Docket: 0756-1551

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

- 1 -

In re PATENT Application of:

| Shunpei YAMAZAKI et al. |)
| Serial No. 08/691,434 |) Art Unit: 1107
| Filed: August 2, 1996 |) Examiner: Wilczewski
| For: METHOD OF FABRICATING |)
| SEMICONDUCTOR DEVICES |)

AND APPARATUS FOR)
PROCESSING A)

SEMICONDUCTOR) Date: September 15, 1997

RESPONSE TO ELECTION REQUIREMENT

Honorable Assistant Commissioner for Patents

Washington, D.C. 20231

Sir:

In response to the election requirement in the Office Action of July 16, 1997, Applicants hereby elect without traverse the second species of the claimed invention as recited in claims 16, 17, 18, 19, 20, 24, and 25 in which the semiconductor processing apparatus includes a vacuum chamber, an ion introducing apparatus, and a laser processing apparatus and the second subspecies as recited in claims 56-61 in which the semiconductor processing apparatus includes a vacuum chamber, an ion introducing apparatus, and a laser

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processing apparatus and in which the rectangular-shaped laser beam has a width greater than the width of the "substantially" square substrate.

Examination on the merits is requested.

Respectfully submitted,

Gerald J Ferguson, Jr.

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